

Indium Evaporation System

Model: SA-VKT550I

SA-VKT550I is a custom-built thermal resistance evaporation platform, specially optimized for ultra-precise indium bump formation. Boasting consistent reliable output, comprehensive automated operation and low upkeep costs, it fully satisfies stringent process standards for advanced flip-chip interconnection and bonding.



Feature

- Low cost
- Easy operation
- Customize
- Mass production

Application

- Laser
- R&D
- Integrated circuit
- MEMS

Specifications:

Parameter	Descriptions
Power Supply	8kW(max.)
Workpiece Angle	-45°~45°, adjustable
Film thickness monitoring	Crystal oscillator controller
Ion Source	Kaufman & Hall ion source
Fixture types	Dome & Knudsen & Plate
Pumping System	Cryopump / magnetically levitated turbo-molecular pump + Dry mechanical pump
Coating Uniformity	±3%
Coating Repeatability	±2%
Uniform Deposition Area	Ø300 mm(max.)
Ultimate Vacuum	1E-5Pa
Vacuum Measurement	Full-range vacuum gauge
Temperature Control Range	-80~200℃
Space Requirements(L×W×H,m)	3.3×2.7×2.2

Principle:

